

FIG. 1

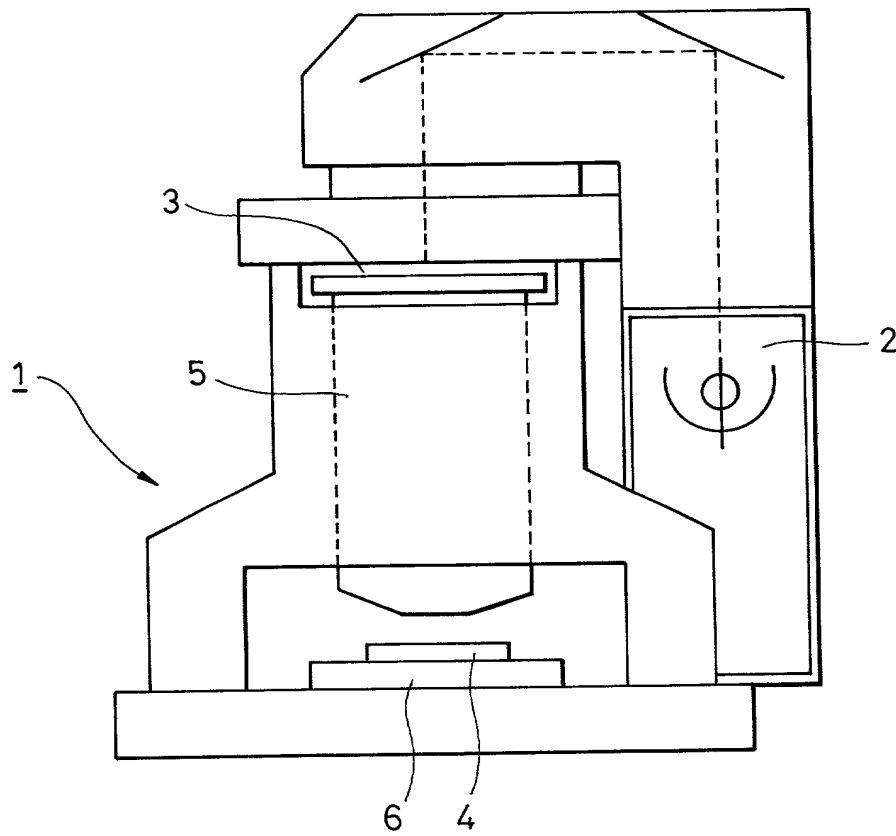
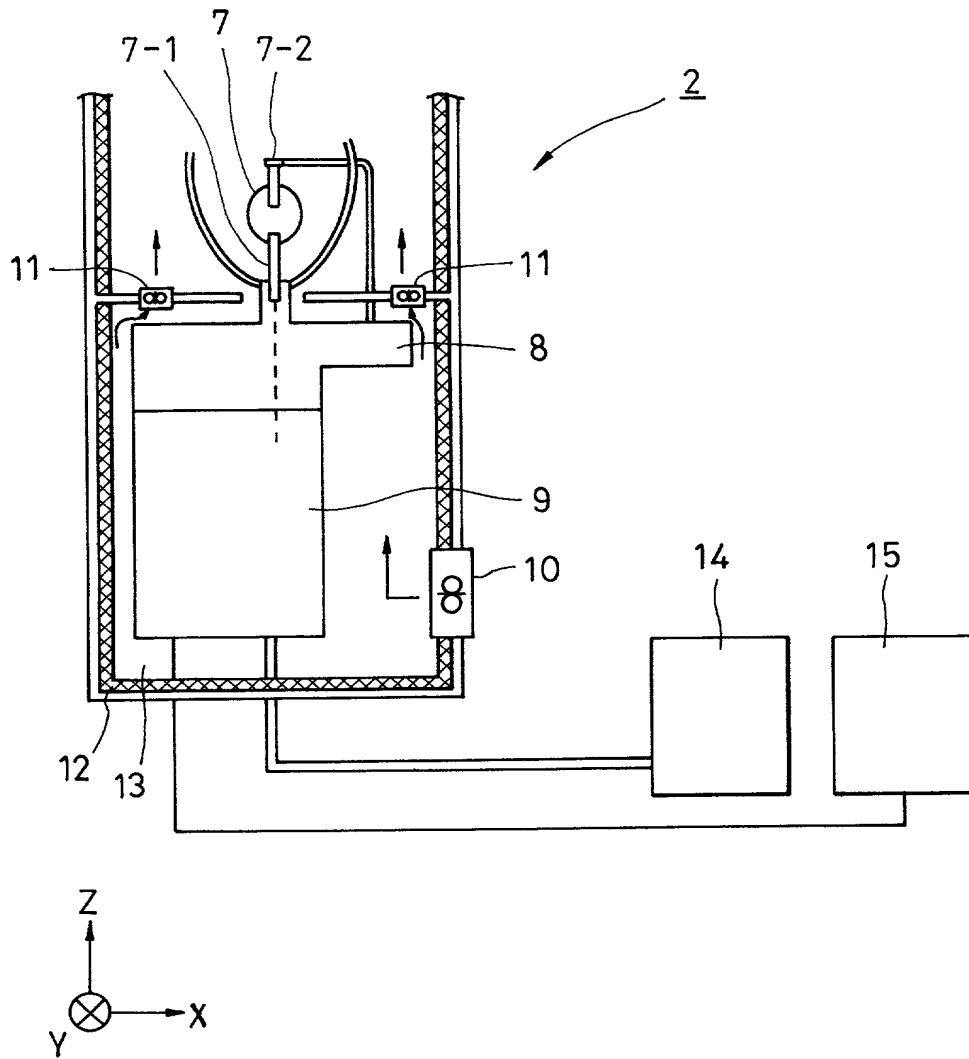


FIG. 2



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FIG. 3

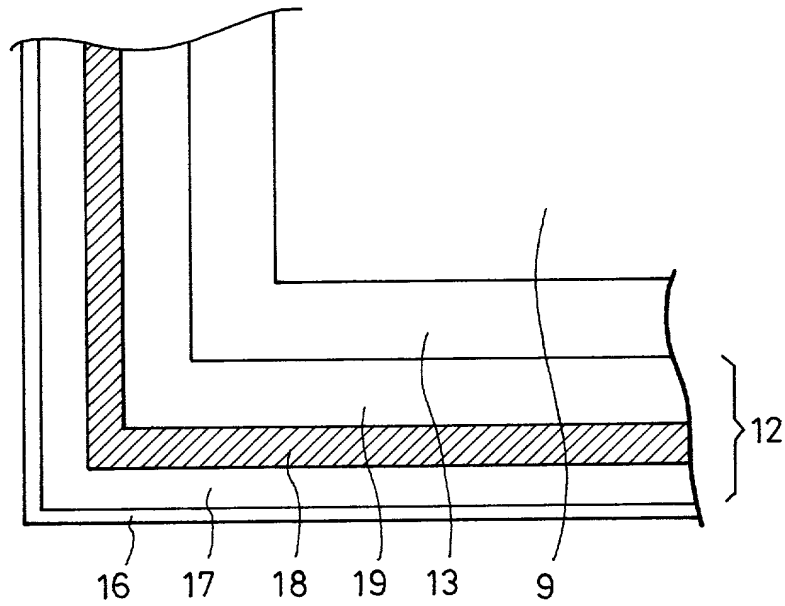


FIG. 4

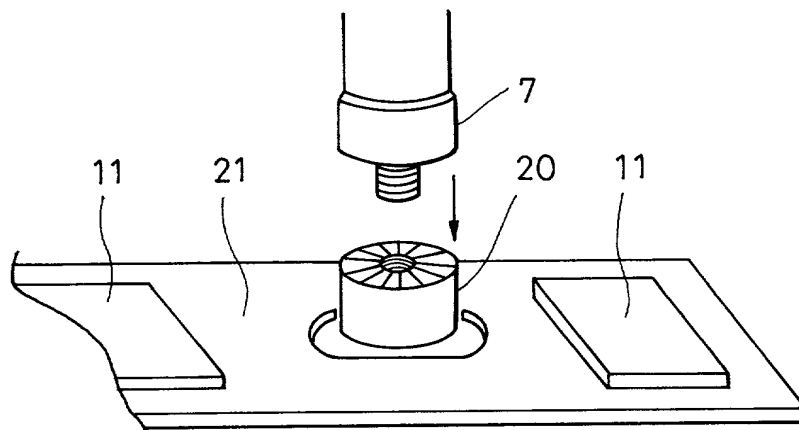


FIG. 5

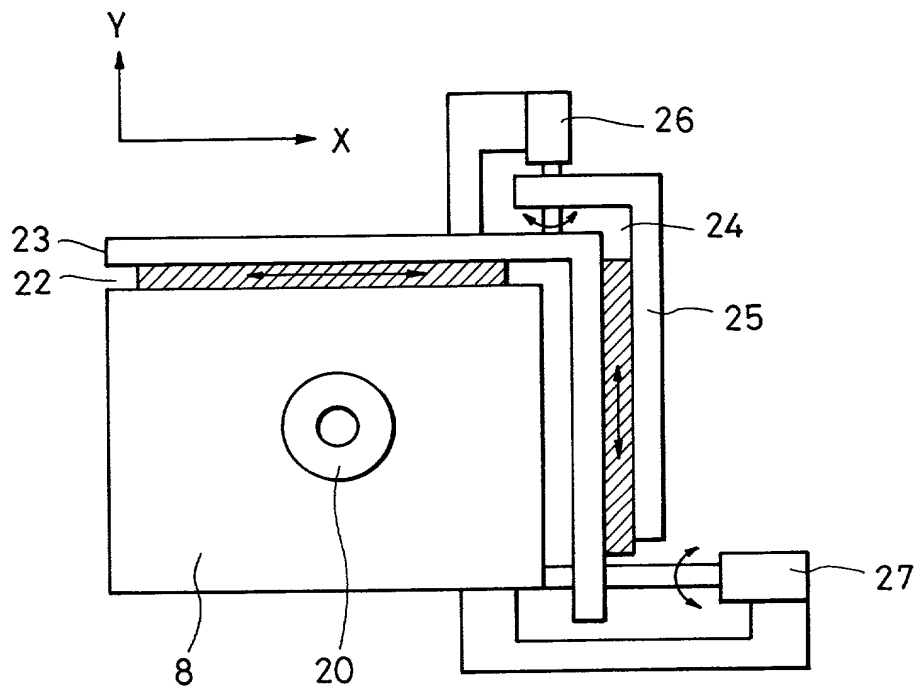


FIG. 6

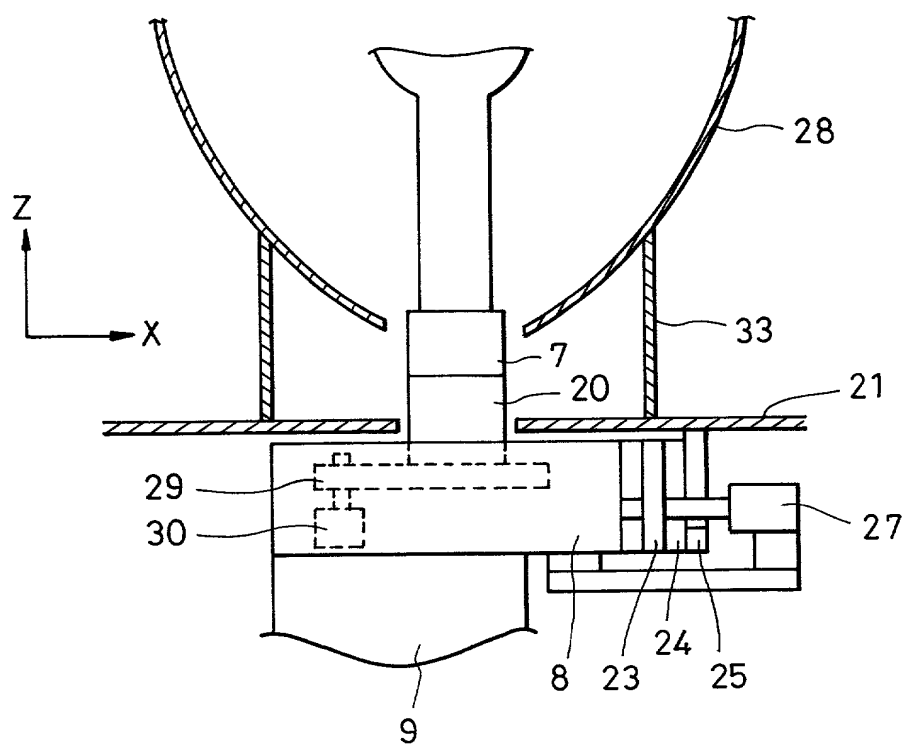


FIG. 7

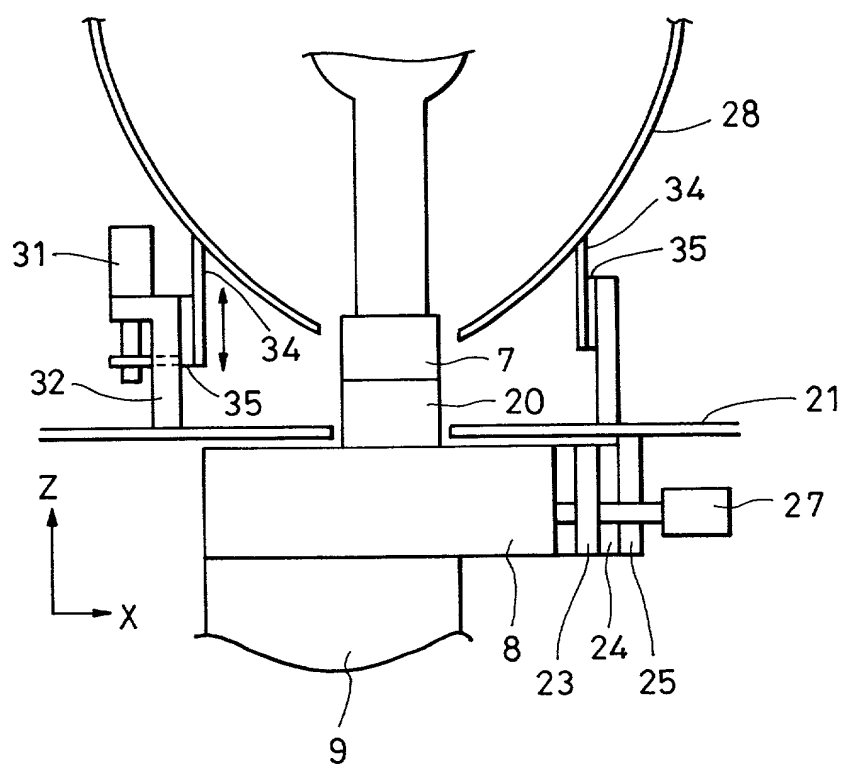
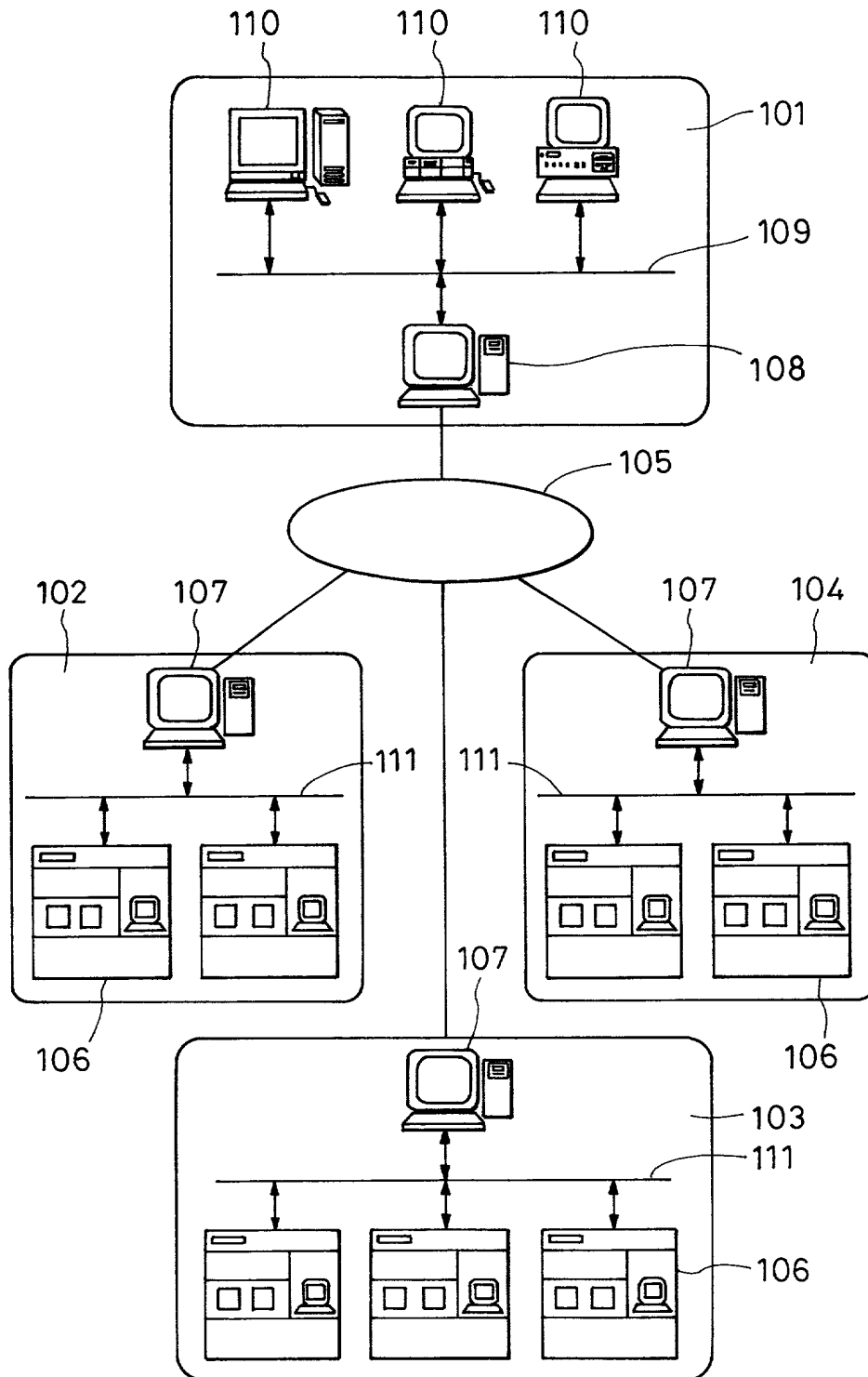
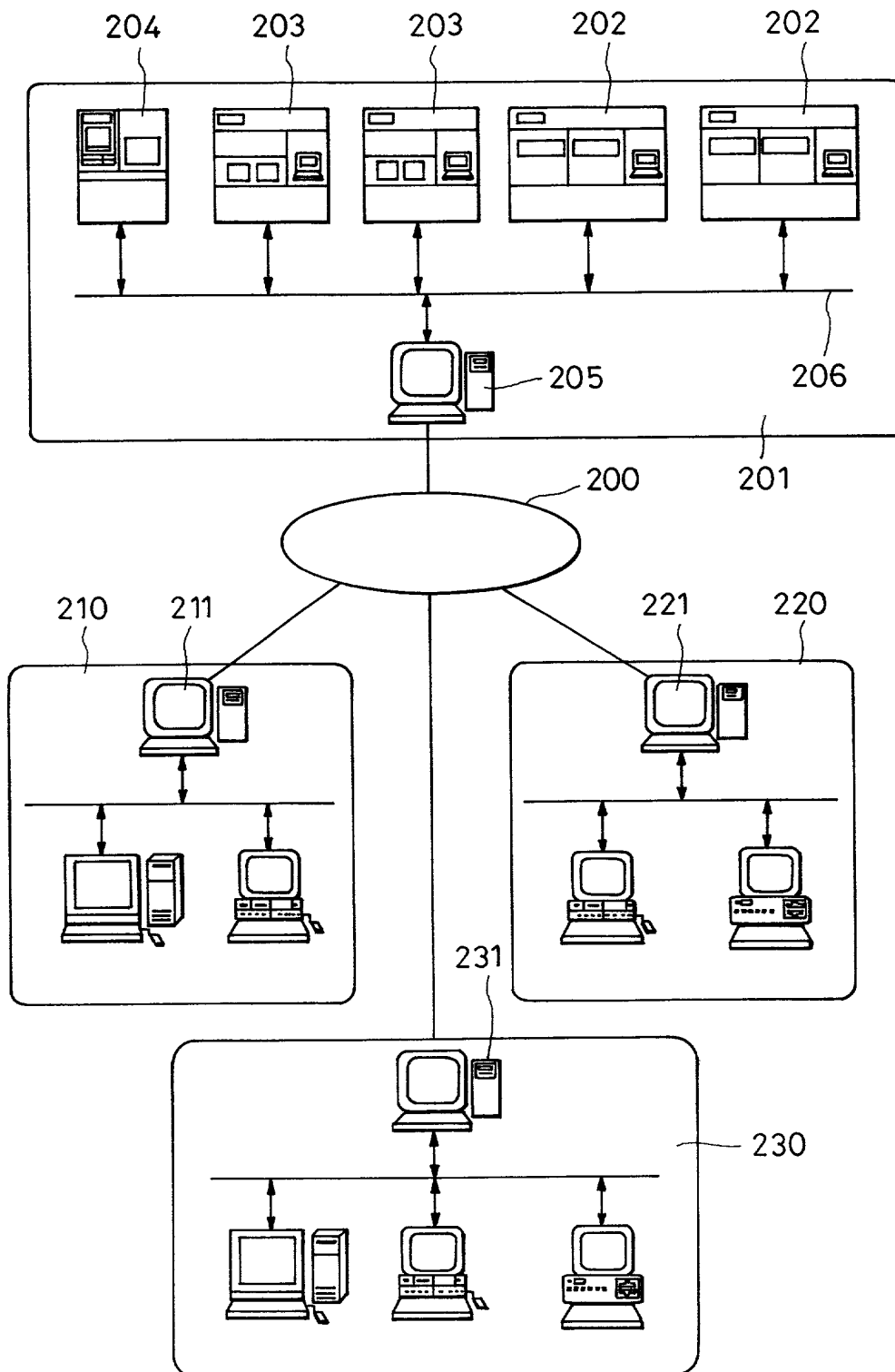


FIG. 8



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FIG. 9





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FIG. 10

URL

TROUBLE DATABASE INPUT SCREEN

DATA OF OCCURRENCE  404

MODEL  401

TITLE  403

EQUIPMENT SERIAL NO.  402

URGENCY  405

SYMPTOMS  406

MEASURES  407

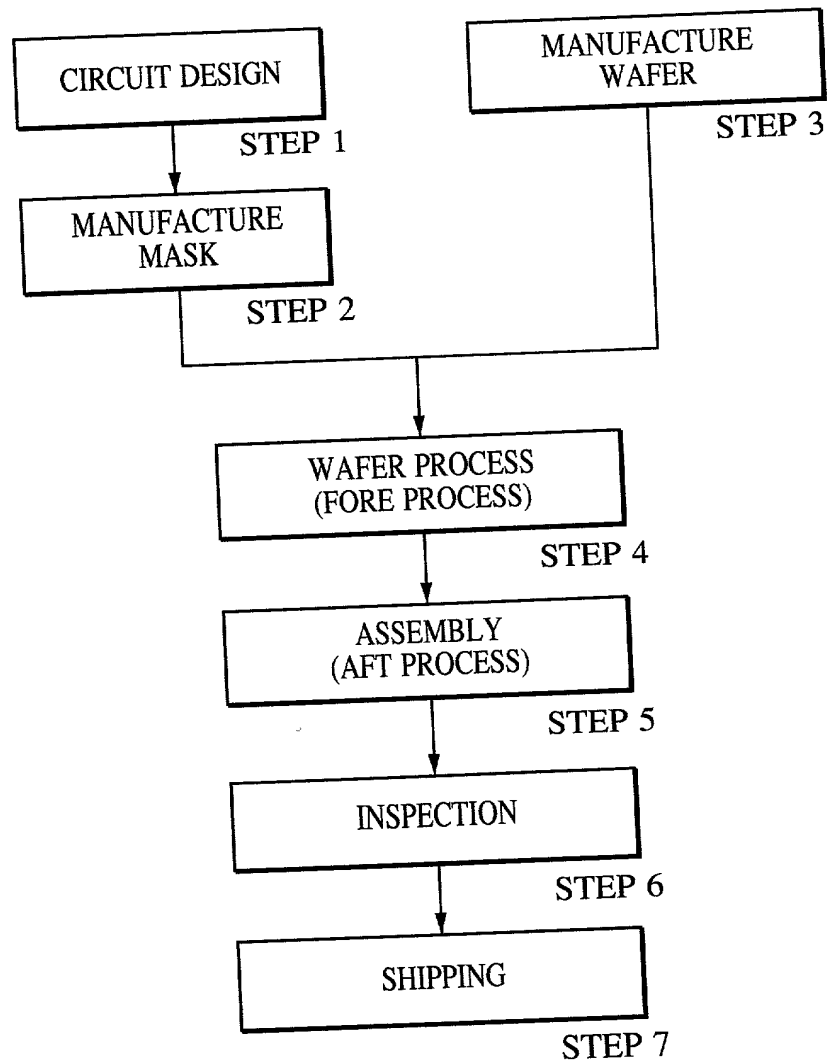
RESULTS  408

410

[LINK TO DATABASE OF LIST OF RESULTS](#) 411 [SOFTWARE LIBRARY](#) 412 [OPERATING GUIDE](#)

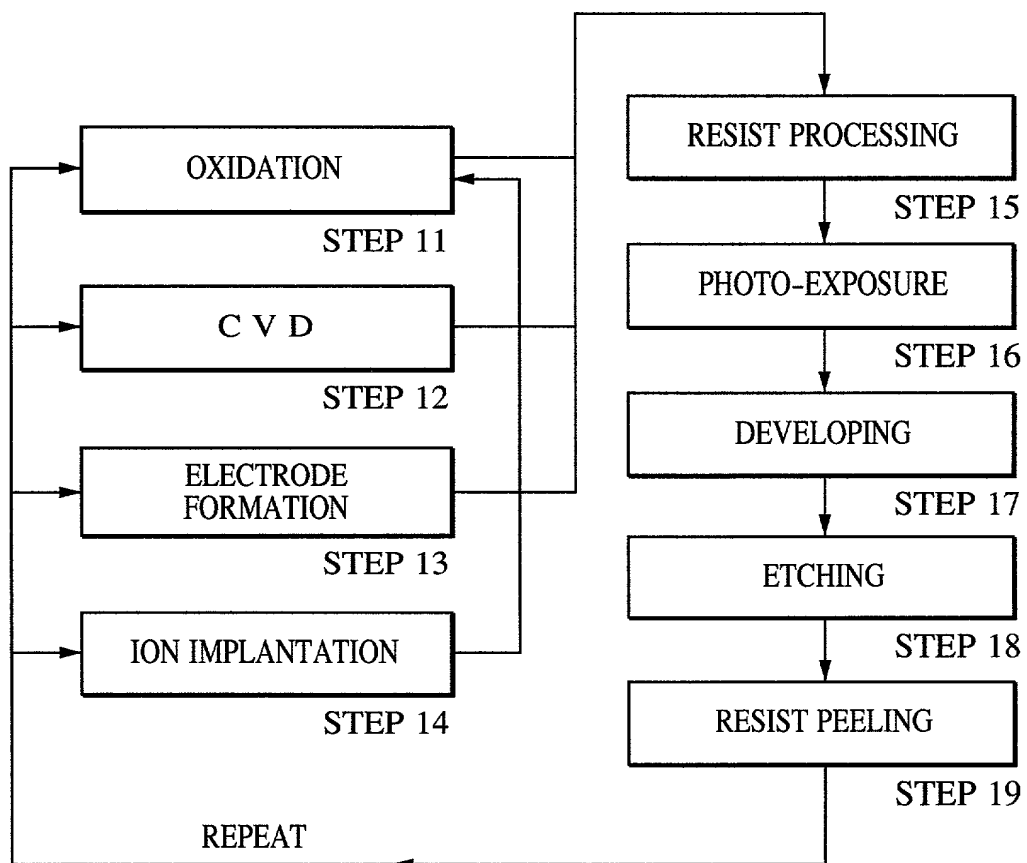
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FIG. 11



FLOW FOR MANUFACTURING SEMICONDUCTOR DEVICES

FIG. 12



WAFER PROCESS